## RESPONSE UNDER 37 CFR 1.116 EXPEDITED PROCEDURE **EXAMINING GROUP 1765**

PATENT APPLICATION Docket No.: 9898-314

Client Ref. No.: SS-20035-US

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Won-Jun LEE, et al.

Serial No.:

10/763,356

Examiner:

Anita Karen Alanko

Filed:

January 23, 2004

Group Art Unit:

1765

Confirmation No.:

7097

For:

ETCHING METHOD FOR MANUFACTURING SEMICONDUCTOR

**DEVICE** 

Date:

August 17, 2007

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## **AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR 1.116**

Responsive to the Final Office Action, Paper No. 20070514, dated May 17, 2007, please amend the application as follows.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.